



Alcatel ATH-500M

Technical Specifications

		ATH 500 M		ATH 500 MT
Rotational Speed	rpm	50000		
Inlet Flange		DN100	DN160	DN160
Pumping Speed with inlet screen	N ₂ l/s	300	500	500
	Ar l/s	270	500	500
	He l/s	270	340	340
	H ₂ l/s	170	190	190
Compression ratio	N ₂	2 x 10 ⁷		
	Ar	8 x 10 ⁶		
	He	1 x 10 ⁴		
	H ₂	2 x 10 ²		
Ultimate Pressure	mbar	< 1 x 10 ⁻⁸		
Recommended Purge Flow Rate	sccm	50		
Maximum continuous inlet pressure N ₂ *	mbar	1	1.2	0.02
Maximum continuous exhaust pressure N ₂ **	mbar	1.7	1.8	1.7
Maximum throughput N ₂ (M: cold, MT: 65°C)*	sccm	3000		500
Maximum heating temperature	°C	N/A		65
Maximum baking temperature	°C	120		
Vibration level (displacement)	µm	< 0.01		
Recommended backing pump		ACP40		
Recommended cooling water flow rate	l/hour	60		
Cooling water temperature	°C	15-25		
Mounting orientation		Any		
Exhaust flange		DN25 ISOKF		DN40 ISO KF
N ₂ purge flange		1/8G (ISO228)		1/4VCR
Start up time (maximum)	mn	< 2.5		
Pump weight	kg (lb)	17 (37)		18 (39)
Remote Controller type		N/A		
Controller weight	kg (lbs)	N/A		
Start up Power	Watt	560		
Nominal Power	Watt	100		
Controller power supply		48 VDC		
Stainless steel inlet screen (factory setting)		yes		
OBC (on-board-control) control option	Profibus	yes	no	
	Remote	yes		
	Device net	no		

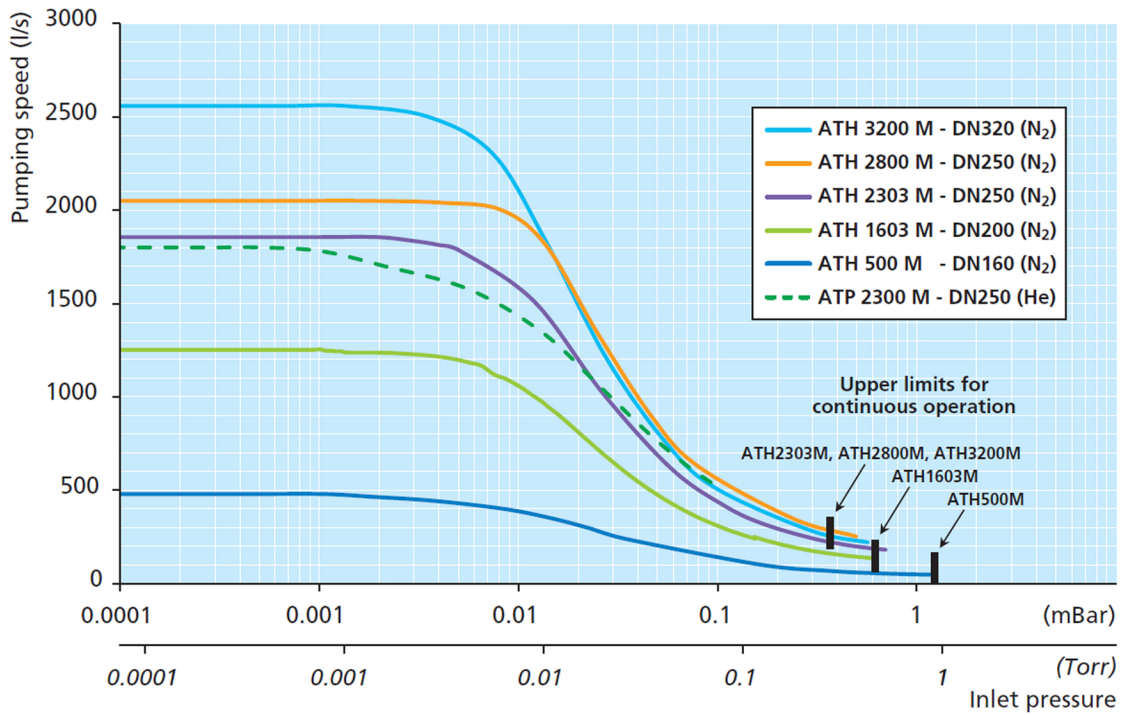
*Depends on external conditions of water temperature, water flow, environment temperature

** Exhaust pressure limit without flow speed loss. Depends on certain external condition

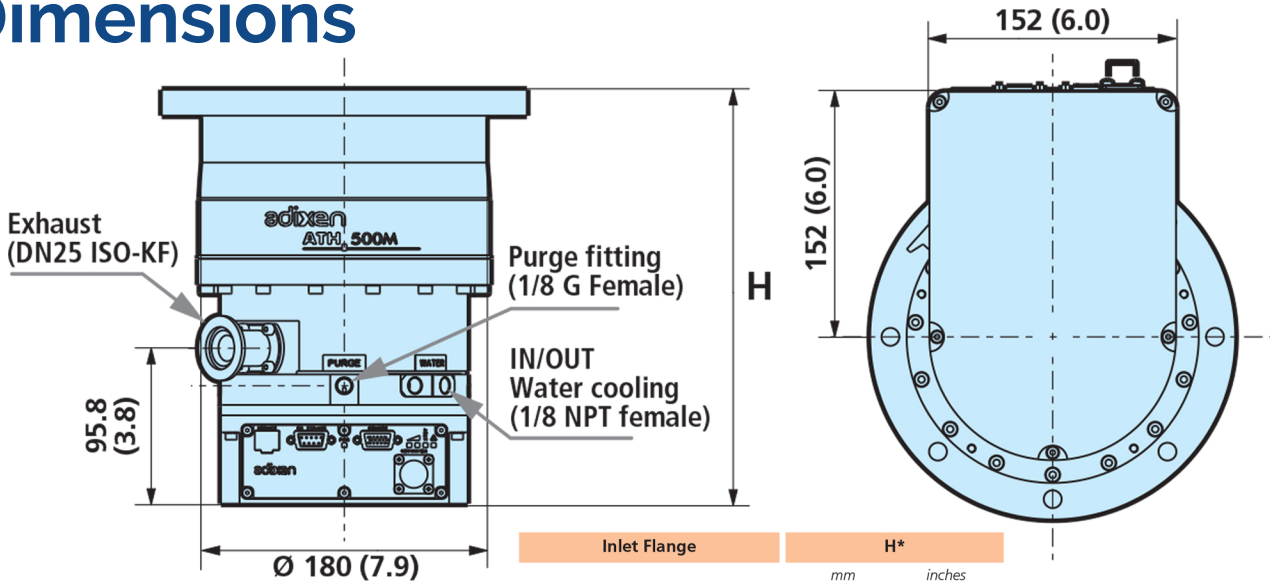


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Pumping Curves



Dimensions



Inlet Flange	H*	
	mm	inches
DN 160 ISO-F	256	10.1
DN 160 ISO-K	256	10.1
DN 160 CF-F	277	10.9
DN 100 ISO-K	296	11.7
DN 100 CF-F	306	12.1



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PHONE: 831-462-8900

FAX: 831-462-3536

WWW.PROVAC.COM

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Features & Benefits

- installation in any orientation
- heated version available for corrosive applications
- integrated electronic controller
- lubricant-free magnetic bearings
- high throughput for all process gases

Applications

- surface analyzers • leak detectors • biotechnology • residual gas analysis • bonding • medical technologies • isolation vacuums
- heat treatment • nanotechnology • semiconductor • coating
- research & development

